



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Eiji NATORI

Application No.: 09/819,688

Filed: March 29, 2001

For: METHOD AND DEVICE FOR MANUFACTURING CERAMICS,
SEMICONDUCTOR DEVICE AND PIEZOELECTRIC DEVICE

Group Art Unit: 2813

Examiner: D. Hogan

Docket No.: 109120

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Normal
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AMENDMENT UNDER 37 C.F.R. §1.111

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

In reply to the April 10, 2002 Office Action, please amend the above-identified application as follows:

IN THE CLAIMS:

Please cancel claim 14 without prejudice to or disclaimer of the subject matter contained therein.

Please replace claim 1 as follows:

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1. (Amended) A method for manufacturing ceramics comprising a step of forming a ceramic film on a substrate by mixing a fine particle of a raw material species which becomes at least part of raw materials for ceramics with an active species, and feeding the mixed fine particle and active species to the substrate, wherein the ceramic film is formed by an LSMCD process or a misted CVD process.